Novel Device laboratory

新器件实验室

Position-Sensitive SiPM 11-2727PS Series

Features

In contrast with a conventional SiPM, NDL SiPM employs intrinsic epitaxial layer to form the quenching resistors, using a continuous silicon caping layer as an anode to connect all the APD cells. As a result, the device has more compact structure and simpler fabrication technology, allows larger micro-cell density (larger dynamic range) while retaining adequate photon detection efficiency (PDE). Furthermore, NDL SiPM benefits to implement a two-dimensional (2D) tetra-lateral position-sensitive (PS) SiPM, which has attractive advantages of less output electrodes, simple readout electronics and high position resolution.

- **Simple Readout Electronics**
- **\(\)** High Position Resolution
- **❖** Large Dynamic Range While High PDE
- **❖** Fast Rise Time and Short Pulse Width
- **Short Recovery Time and High Time Resolution**
- **Cost Effective**

Applications

- **❖** High Energy Physics
- Scintillation Measurement
- **❖** Nuclear Medical Imaging (PET, SPECT, CT)
- * Radiation Detection and Imaging
- **Optical Spectroscope**
- ***** Other Low Level Light Detection

Specifications

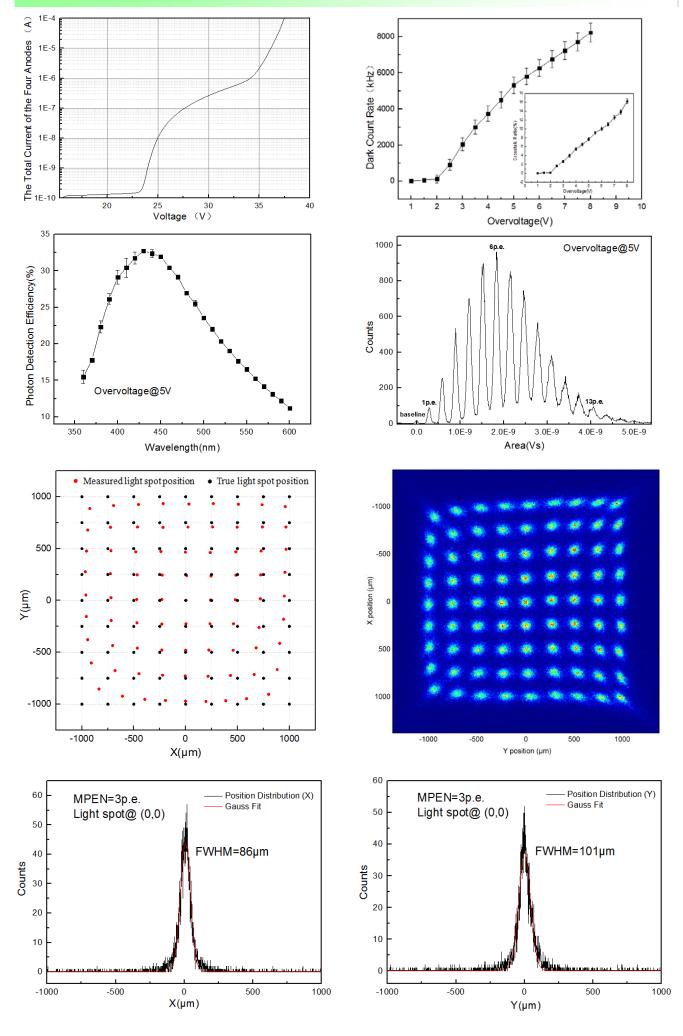
Parameter	Value	Parameter	Value
Effective Active Area	2.77×2.77 mm ²	Peak PDE@420nm*	>31%
Effective Pitch	~10 µm	Dark Count Rate*	~6 MHz
Micro-cell Number	~76729	Gain	≥2×10 ⁵
Operating Temperature Down to LN2 (77 K)	Yes	Breakdown Voltage (V _b)	25.5±0.4 V
Max. Overvoltage (ΔV_{max})	8 V	Sheet Impedance (R ₀)	~440 Ω
Position Algorithm (X)	$x_0 = \frac{L}{2} \cdot \frac{\left(\frac{R_0}{R_s} + 8.7492\right) \left(Q_4 - Q_3\right) \left[\left(\frac{1.7R_0}{R_s} + 5.8156\right) \left(Q_1 + Q_2\right) + \left(\frac{R_0}{R_s} - 5.8156\right) \left(Q_3 + Q_4\right)\right]}{\left[\frac{R_0}{R_s} \left(Q_1 + Q_2 + Q_3 + Q_4\right)\right]^2 - \left[1.02\left(\frac{R_0}{R_s} + 8.7492\right) \left(Q_2 - Q_1\right)\right]^2}$		
Position Algorithm (Y)	$y_0 = \frac{L}{2} \cdot \frac{\left(\frac{R_0}{R_s} + 8.7492\right) (Q_2 - Q_1) \left[\left(\frac{R_0}{R_s} - 5.8156\right) (Q_1 + Q_2) + \left(\frac{1.7R_0}{R_s} + 5.8156\right) (Q_3 + Q_4)\right]}{\left[\frac{R_0}{R_s} (Q_1 + Q_2 + Q_3 + Q_4)\right]^2 - \left[1.02 \left(\frac{R_0}{R_s} + 8.7492\right) (Q_4 - Q_3)\right]^2}$		

^{*} Measured at overvoltage close to 5V. L is the length of the active area (i.e., 2.77mm). Rs is the input impedance. Qi, (i = 1, 2, 3, 4) is the shared charge of the corresponding anode.

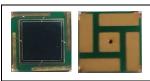


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Characteristic Curves (Temperature: 20℃)



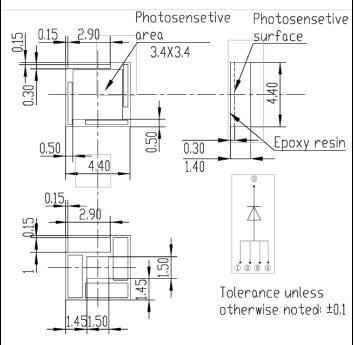
Dimensional outlines (unit: mm)

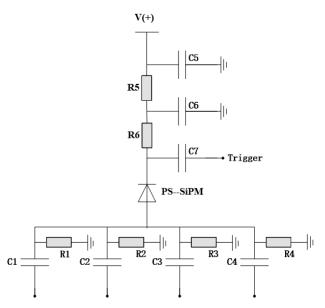


11-2727PS-S

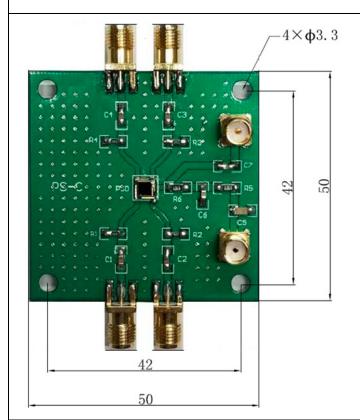
Basic connection diagram for PS Evaluation Board







11-2727PS-E



References

- **1.** "New Distortion Correction Algorithm for Two-Dimensional Tetra-Lateral Position-Sensitive Silicon Photomultiplier." *IEEE Electron Device Letters* 38 (2017): 228-231.
- **2.** "High-Time Resolved Two-Dimensional Tetra-Lateral Position-Sensitive Silicon Photomultiplier." *IEEE Electron Device Letters* 39 (2018): 232-235.
- **3.** "One-dimensional single-photon position-sensitive silicon photomultiplier and its application in Raman spectroscopy." *Optics. Express* 25 (2017): 22820-22828.

Note: Performance and device structure of 11-2727PS products may be different from those published in references!